

★ OMIT/

S02

1999-497716/42

★ JP 11211593-A

Pressure detector mounting structure for etching gas supply system used during semiconductor manufacture — has pressure foot which presses pressure support portion upper surface of sensor box, downwards

OMI T 1998.01.20 1998JP-008841

(1999.08.06) G01L 9/04, G01L 19/00, 19/06

Addnl. Data: FUJIKIN KK

(FUJI-)

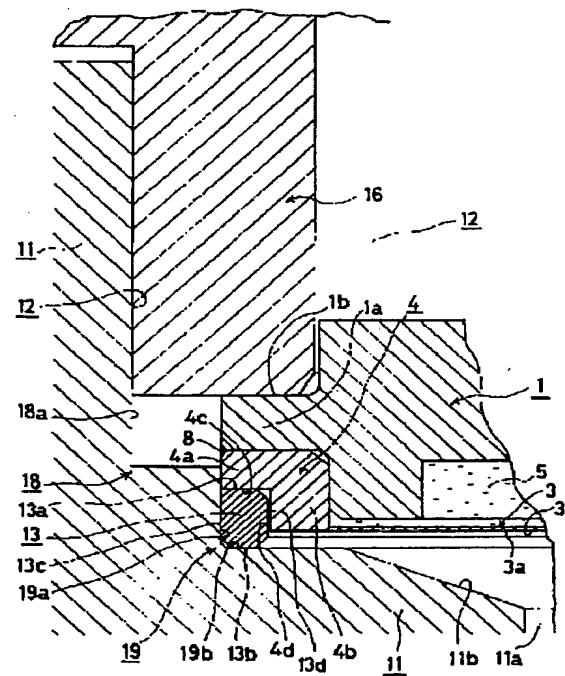
NOVELTY - The attachment tool (11) is fixed to the box (4) of diaphragm (3). Based on the variation of diaphragm, a sensor (1) of a detector is operated. The support portion upper surface (16) of sensor base (1) is pressed downwards by a pressure foot (16). **DETAILED DESCRIPTION** - Projection portions (18,19) are provided at lower portion at hole of attachment tool (11). A rectangular gasket (13) is attached within the hole supports (1a,4a) provided at upper portion of detector and diaphragm box (4a), respectively.

Use: For etching gas supply system used during semiconductor manufacture.

Advantage: Temperature and output characteristic before and after mounting attachment tool is reduced, thereby practical failure is eliminated. **DESCRIPTION OF DRAWING(S)** - The figure shows the front elevation of diaphragm type pressure detector. (1) Sensor; (4) Box; (1a,4a) Hole supports; (3) Diaphragm; (4) Box; (11) Attachment tool; (13) Rectangular gasket; (16) Upper surface; (18,19) Projection portions. (9pp Dwg.No.1/10)

N1999-370897

S02-F04B1; S02-F04E



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